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## Packaging Challenges In High Performance Computing

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Even less than twenty years back, packaging was considered an afterthought by most of the industry, though the high performance computing segment was the first to devote significant resources for optimizing the package performance. Starting with the C4 flip-chip package, there have been steady improvements in high performance packaging including having interconnects greater than 10,000, pitch less than 200  $\mu\text{m}$ , migration from ceramic to organic substrates, and from high-lead to lead-free interconnects. But fundamental challenges remain, and the ones that impact packaging are: (i) cost-effective manufacturing with interconnects at finer pitch than 150  $\mu\text{m}$ , (ii) mitigating the failures induced by high currents due to the phenomenon termed electromigration, (iii) reliability of low-k dielectrics and interconnects under thermo-mechanical loads, and (iv) materials and assembly issues. The industry is addressing these issues through (i) substrate development including solder on pad application improvements, (ii) interconnect modifications to avoid Copper depletion and creation of voids, (iii) optimizing the underfill properties to balance the stresses in the low-k dielectric and interconnects, and (iv) underfill process improvements using jet or vacuum dispense.

The one feature that has the most impact on the above mentioned issues is the interconnect structure. The current ones in the industry include high-lead solder bump, lead-free bump, copper core, copper post, etc. In this article, an interconnect structure called  $\mu\text{PILRTM}$  interconnect is presented in detail as it addresses each of the four challenges identified above. It consists of a substrate manufacturing technique that results in a copper structure on a substrate pad. This eliminates the need for applying solder on substrate, which is an issue at finer pitches. Due to the presence of copper structure, the failure due to electromigration phenomenon is significantly delayed on the substrate side due to the fact that there is enough copper to eventually form a relatively stable intermetallic, which has much lower migration rate compared to copper in tin. This retards the void growth and hence improves reliability. Due to the 3D nature of the  $\mu\text{PILR}$  interconnect, the aspect ratio (height to diameter) is higher than a solder bump; which eases the package assembly issues such as interconnect joints yield, underfill voids, etc. Finally, the reliability is improved because the fracture toughness of the  $\mu\text{PILR}$  interconnect is higher than solder bump as the

$\mu$ PILR structure acts as a fatigue crack growth inhibitor. It also offers better low-k dielectric reliability as the lead-free solder interface on the chip side exerts lower stress than the copper post on chip. This article presents design, simulation, substrate manufacturing, package assembly, electromigration and reliability results for a test vehicle representing CPU applications.

### Flip-chip interconnects

There are three main types of flip-chip interconnect being used in the industry: high-lead bump, lead-free bump and copper post. The high-lead bump is being phased out due to ROHS requirements. The lead-free bump has fine-pitch limitations due to solder collapse and has low electromigration performance. The copper post is emerging as an option for high performance packaging as it offers fine pitch capabilities and has good electromigration performance. Some of the issues with copper post on chip are lower reliability with extreme low-k dielectrics and relatively higher cost. In this paper, a new type of flip-chip interconnect called  $\mu$ PILR is presented that offers the advantages of copper post on chip (fine pitch and good electromigration performance) while offering good reliability and lower cost.

The typical failure modes seen in interconnects are related to interconnect reliability (solder joint fatigue life), package reliability (low-k dielectric cracking) and package performance (voiding due to electromigration phenomenon from high current densities). A new interconnect design has to address these issues while offering a roadmap to fine-pitch well below 100  $\mu\text{m}$  and be able to be manufactured using conventional industry equipment and materials. The  $\mu$ PILR interconnects consist of an array of solid copper pillars that are part of the substrate. Depending on the method of manufacturing, these interconnects have different sizes and shapes, and can be joined to chips with or without copper posts. Some of the different configurations.

### $\mu$ PILR substrate

The  $\mu$ PILR substrate can be manufactured with or without laminate core. The coreless method consists of starting with a copper sheet as the base layer, carrying out the build-up process to the required number of layers and then processing the copper sheet to form  $\mu$ PILR interconnects. The core-based substrate approach consists of starting with a conventional substrate and then attaching a copper sheet and forming  $\mu$ PILR interconnects.

The main technical challenges in this process are:

- Uniformity of joining layer and its surface properties
- Formation of  $\mu$ PILRs through various techniques

- Removing of joining layer and intermetallics without damaging the top circuit layer and Uniformity of solder mask and alignment

Figure 1 shows the  $\mu$ PILR interconnects on the substrate. As they are formed from a copper sheet, the measured co-planarity was excellent ( $\pm 2 \mu\text{m}$ ).

The substrates underwent conventional hot oil tests (20-260 °C, 50 cycles) successfully. Bump shear tests were done before and after ageing (150 °C, 1000 hours) and the shear force was in 40-60 gm range, well above the required 35 gm force.

#### Test vehicle design and assembly

The test vehicle was designed to represent a high computing application. The chip measured 20 mm x 18 mm x 0.75 mm with 10,132 interconnects at 0.15 mm (signal) and 0.2 mm (power/ground) pitch. The substrate measured 40 mm x 40 mm x 1.2 mm and had 10 metal layers in a 3-4-3 build-up on core stack. The interconnect details along with the package cross-section are given in Figure 2.

The package assembly was done using conventional flip-chip equipment and processes. After process optimization, both flip-chip reflow and underfill processes were close to 100% yield. Figure 3 shows the package assembly results. After the underfill process, the heat spreader was attached with Indium as the thermal interface material (TIM), according to the design as shown in Figure 2.

#### Electromigration performance

For high performance computing, two main requirements are electromigration performance and reliability. The electromigration testing was done under two different conditions. The samples passed 1300 hours without failure under accelerated test conditions of 30.0kA/cm<sup>2</sup> (1.0A) & 1600C and passed 1000 hours without failure under highly accelerated test conditions of 45.0kA/ cm<sup>2</sup> (1.5A) & 1600C. The resistance was monitored continuously and the rise in resistance was less than 3%. There are no voids on the substrate side and void formation can be seen on the chip side.

Compared to published results for high-lead bump, lead-free bump and copper post on chip, these results are the best when the acceleration factors are taken into account. It is estimated that the acceleration factor is approximately 2.5x from 15.0kA/cm<sup>2</sup> to 45.0kA/cm<sup>2</sup>, and about 2x from 125 °C to 160 0C for a total of 5x for 45.0kA/ cm<sup>2</sup> & 160°C compared to 15.0kA/cm<sup>2</sup> & 115°C test conditions. This implies that 1000 hours of successful testing under 45.0kA/cm<sup>2</sup> & 160°C corresponds to about 5000 hours under 15.0kA/cm<sup>2</sup> & 115°C, which is better than the results published in for copper posts on chip.

## Reliability

The reliability simulations were done comparing the copper post on chip and  $\mu$ PILR interconnects under two test conditions, -55 to 125 °C (thermal shock) and 0 to 100 °C (thermal cycling). The  $\mu$ PILR interconnect is expected to pass the reliability tests and is approximately 20% better in fatigue life, which is primarily due to the extra amount of solder. Reliability testing was also done and no failures were observed after 1000 cycles under -55 to 125 °C thermal shock test conditions.

## Conclusions

The packaging performance has to keep improving to meet the ITRS roadmaps and to minimize negatively impacting the performance of the chip and the system. The flip-chip interconnects are the key enablers for better package performance through improvements in fine-pitch, current carrying capacity and reliability. High-lead bumps are being phased out and lead-free bumps have limitations regarding fine-pitch and electromigration performance. Copper post on chip and  $\mu$ PILR on substrate are two interconnect technologies that meet the future packaging requirements, with  $\mu$ PILR expected to perform better in reliability. The reliability benefit gets more pronounced with the transition from low-k to extreme low-k dielectrics on the chip side. More research work is ongoing with  $\mu$ PILR interconnects and more research in general is needed by the industry to ensure that the packaging for high performance computing facilitates excellent electrical and thermal performance while meeting reliability and cost requirements.

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